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(54) Title: APPARATUS OF PLURAL CHARGED-PARTICLE BEAMS

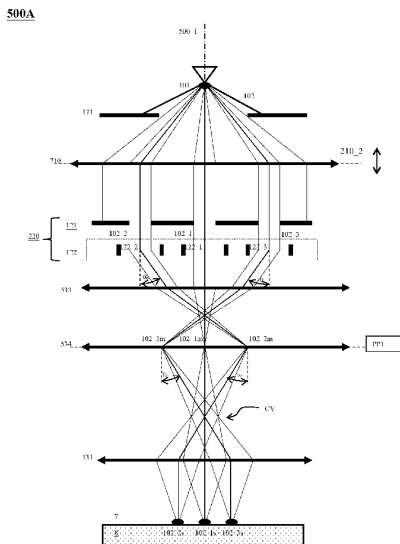


Figure 5B (Invention)

(57) Abstract: A new multi-beam apparatus with a total FOV variable in
size, orientation and incident angle, is proposed. The new apparatus provides
more flexibility to speed the sample observation and enable more samples ob-
servable. More specifically, as a yield management tool to inspect and/or re-
view defects on wafers/masks in semiconductor manufacturing industry, the
new apparatus provide more possibilities to achieve a high throughput and
detect more kinds of defects.

WO 2017/132435 A1

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